

Magnetostrictive Thin Film Galfenol for MEMS Applications

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I Galfenol-coated Si_3N_4

double-clamped cantilevers

- u Beams were magnetically actuated
- u Applications will include microvalves, micropumps, MEMS sensors and actuators

I Mechanical Properties

- u First to measure hardness (5 – 9 GPa) and Young's Modulus (136 -187 GPa) of Galfenol thin films
- u Young's Modulus of thin films is higher than bulk values

I Magnetostriction

- u Measured magnetostriction up to 163 ppm
- u Double peak trend of magnetostriction versus %Ga is similar to bulk Galfenol

